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J. Vac. Sci. Technol. A **32**, 020801 (2014); <http://dx.doi.org/10.1116/1.4820493>

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INTERFACES

Controlled ambient and temperature treatment of InGaZnO thin film transistors for improved bias-illumination stress reliability

Rajitha N. P. Vemuri, Muhammad R. Hasin and T. L. Alford

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Novel method for the prediction of an interface bonding species at alumina/metal interfaces

Michiko Yoshitake, Shinjiro Yagyu and Toyohiro Chikyow

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Second-harmonic intensity and phase spectroscopy as a sensitive method to probe the space-charge field in Si(100) covered with charged dielectrics

Nick M. Terlinden, Vincent Vandalon, Roger H. E. C. Bosch and W. M. M. (Erwin) Kessels

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Determination of subband energies and 2DEG characteristics of Al_xGa_{1-x}N/GaN heterojunctions using variational method

Farzin Manouchehri, Pouya Valizadeh and M. Z. Kabir

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PHOTOVOLTAICS AND ENERGY

Self limiting deposition of pyrite absorbers by pulsed PECVD

Christopher D. Sentman, Maria O'Brien and Colin A. Wolden

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Highly transparent Nb-doped indium oxide electrodes for organic solar cells

Jun Ho Kim, Tae-Yeon Seong, Seok-In Na, Kwun-Bum Chung, Hye-Min Lee and Han-Ki Kim

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PLASMA SCIENCE AND TECHNOLOGY

MD simulations of low energy Cl_x^+ ions interaction with ultrathin silicon layers for advanced etch processes

Paulin Brichon, Emilie Despiau-Pujo and Olivier Joubert

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Plasma damage mechanisms in low k organosilicate glass and their inhibition by Ar ion bombardment

Haseeb Kazi and Jeffrey A. Kelber

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Modeling of inductively coupled plasma $\text{SF}_6/\text{O}_2/\text{Ar}$ plasma discharge: Effect of O_2 on the plasma kinetic properties

Amand Pateau, Ahmed Rhallabi, Marie-Claude Fernandez, Mohamed Boufnichel and Fabrice Roqueta

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Comparison of surface vacuum ultraviolet emissions with resonance level number densities. I. Argon plasmas

John B. Boffard, Chun C. Lin, Cody Culver, Shicong Wang, Amy E. Wendt, Svetlana Radovanov and Harold Persing

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Fabrication of tapered graded-refractive-index micropillars using ion-implanted-photoresist as an etch mask

Ming Ma, E. Fred Schubert, Jaehee Cho, Morgan Evans, Gi Bum Kim and Cheolsoo Sone

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Role of the blocking capacitor in control of ion energy distributions in pulsed capacitively coupled plasmas sustained in $\text{Ar}/\text{CF}_4/\text{O}_2$

Sang-Heon Song and Mark J. Kushner

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Process monitoring during AlN_xO_y deposition by reactive magnetron sputtering and correlation with the film's properties

Joel Borges, Nicolas Martin, Filipe Vaz and Luis Marques

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SURFACES

TOF SIMS analysis and generation of white photoluminescence from strontium silicate codoped with europium and terbium

Modiehi A. Tshabalala, Hendrik C. Swart and Odireleng M. Ntwaeaborwa

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Chemical mechanical planarization of gold

Golnaz Karbasian, Patrick J. Fay, Huili Grace Xing, Alexei O. Orlov and Gregory L. Snider

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THIN FILMS

Reactive sputtering of substoichiometric Ta₂O_x for resistive memory applications

James E. Stevens, Andrew J. Lohn, Seth A. Decker, Barney L. Doyle, Patrick R. Mickel and Matthew J. Marinella

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Properties of zinc oxide films grown on sapphire substrates using high-temperature H₂O generated by a catalytic reaction on platinum nanoparticles

Kanji Yasui, Tomohiko Takeuchi, Eichi Nagatomi, Souichi Satomoto, Hitoshi Miura, Takahiro Kato and Takayuki Konya

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Mechanical and transparent conductive properties of ZnO and Ga-doped ZnO films sputtered using electron-cyclotron-resonance plasma on polyethylene naphthalate substrates

Housei Akazawa

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Mechanical and tribological properties of Sn-Cu-O films prepared by reactive magnetron sputtering

Jindřich Musil, Martin Hromádka, Radomír Čerstvý and Zbyněk Soukup

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Vibrational spectra of CO adsorbed on oxide thin films: A tool to probe the surface defects and phase changes of oxide thin films

Aditya Savara

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